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NV-Series

anoSystem

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More accurate measurement High resolution Multi profile analysis

Company Overview

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Business Fi

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Head Of

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me	NanoSystem Co., Ltd.
E.O	Hyung-Seok Lee Ph.D
ent	24, April 2003
eld	Non-Contact Surface Measurer
	High Density PCB Measuremer
	Semiconductor, FPD Display M
	Automotive Industry Field
uct	Non-Contact 3D Surface Profile
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- NanoSystem is a high-tech company that manufactures optical 3D surface measuring instruments and provides effective and easy-to-use 3D image and measurement values in micro and nano unit areas.
- Headquartered in South Korea, Daejeon has partners in Asia, Europe and China to provide services that actively respond to customer needs.
- We are developing and producing innovative products for shape and roughness measurement of ultra-precision field by supplying NV, NVM series and measurement solution, which are non-contact optical measuring instruments to Korean, Japanese, Chinese and European customers.

Leading measurement and inspection technology in the world, Global Leader NanoSystem



ment-Inspection Equipment

nt Field

leasurement · Inspection Field

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"Leading measurement and inspection technology in the world, Global Leader NanoSystem"

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NV-1800

NanoView 3D Surface Profiler

Company History

2006 2003~2006

- Company Establishment of NanoSystem Co., Ltd - Registration of Venture - Get Grand Prize in The 5th National Contest of Business Incubator Center (SMBA) - Acquire Certificate of Superior Technology Company (Korea Technology Credit Guarantee Fund) - Be Selected as Demonstration Business of Development in Technology (Industrial Bank of Korea)

- First business with Samsung Elecro-mechanics (Daejeon) - Nano View, Excellent and Exemplary product selected by the sponsor of Daejeon megalopolis

- Acquire ISO9001:2000 (Certification Number : K-QA-Q041816) - Head Office Transfer (1695-2 Sinil-dong, Daeduk-gu, Daejeon, Korea)

2012 2007~2012

- Export great promise midsize business selection (Small & Medium Business Administration) - Acquire Promising Small & Medium Business (Daejeon Megalopolis) - CE certification acquisition (Model : NVE-1000 Certification Number : K1491/E06)

- CE Certification acquisition (Model : NVM-4151P/NVM-5161P Certification Number : K1492/E06)

Yuseong-Gu, Daejeon, South Korea)

Present 2013~Present - Opened Chongqing office in China - Selected as a company that wants to get a job in 2013(Innobiz Association) - Won the prize of million dollar export(Korea International Trade Association) - Selected Korea's best industrial technology achievement in 2014 - Certified as promising small and medium-sized business(Daejeon City) - Designated as a human resource development type small and medium-sized business(Small and Medium Business Administration)



- Nidec Read Company(JAPAN) Business partnership contracting & export

- INNO-BIZ Selection (Small & Medium Business Administration) - An office building completion & Head office transfer (Gwanpyoung-dong,

- The Great cooperation of business (Samsung Corning Precision Glass - SCP)

General Model NV Series

Create A New Solution for Precise Measuring of Surface

\gg We are participating in the standardization of ISO, ASEM, DIN, JIS, etc.

The NV-Series have high scan speed with sub-nm vertical resolution(0.1nm), regardless of magnification. Using probe tip/tilt function, NV-Series are able to measure even highly sloped surface. NanoSystem's own patented hardware and software for NV-Series are greatly intuitive to use and having user friendly interface.

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Also, NV-Series can virtually measure any surface and show vivid 3D images immediately such as texture on rough, transparent samples and more. NV-Series perform 2D and 3D multi functional results.

NV-Series is high performance optical measurement solution that is recognized in the laboratory as well as in the production process.

Advanced Measuring Technology

» White Light Scanning Interferometry

A condenser lens collimates the light from the broadband light source. A beam splitter separates the light into reference and measurement beams.

The reference beam is reflected by the reference mirror, while the measurement beam is reflected or scattered from the test surface. The returning beams are relayed by the beam splitter to the CCD image sensor, and form an interference pattern of the test surface topography that is spatially sampled by the individual CCD pixels.



» Phase Shifting interferometry

Phase shifting interferometry is a well established technique for areal surface characterization that relies on digitization of interference data acquired during a controlled phase shift, most often introduced by controlled mechanical oscillation of an interference objective.

It provides full 3D images with typical height measurement repeatability of less than 1 nm independent of field size.





Advantages of White Light Scanning Interferometry

» Non-Contact, Non-Destructive, Fast Measurement

Stylus instruments cannot measure micro asperities less than the stylus tip diameter. The white light interferometry can measure the surface roughness of micro geometries at a considerably higher resolution due to a minute light spot size.



The stylus is made of hard material such as sapphire or diamond. Therefore, the surface of the object may be scratched. On the other hand, White Light Scanning Interferometry can measure in a non-contact method and does not damage the surface of the object.





» Greater Reduction of Measurement Time



» Strength of area scanning measurement method

Unlike the method of scanning every point in the filed of view, WSI has the area scanning.



High Tracebility and Repeatability

NV Series is calibrated by an VLSI Step Height Standards sample, certified by the NIST. Achieves extremely high accuracy and repeatability as a height measurement system.



85.8 nm VLSI STEP HEIGHT STANDARD Repeatability / PSI Mode





Unlike the method of scanning every point in the filed of view, WSI has the advantage of reducing the measurement time by measuring

7.75 um VLSI STEP HEIGHT STANDARD Repeatability / WSI Mode

No	Step Height (Unit : um)
1	7.75224
2	7.75031
3	7.75459
4	7.74956
5	7.75383
6	7.75012
7	7.74795
8	7.75157
9	7.75310
10	7.75149
11	7 74939
12	7.74668
13	7 75050
1.4	7.75087
15	7.75021
16	7.75315
17	7.75087
18	7 75048
19	7 74801
20	7 74652
21	7 74806
22	7.75081
23	7.75173
24	7.74979
25	7.74795
26	7.74831
27	7.75076
28	7 75332
29	7 74828
30	7 74806
AVG	7,7503
STD	0.0021



WSI Standard Deviation : 0.0021 µm

Main Feature and Benefits

» Tip-Tilt Probe

The rotation center of the probe is on the focal point of objectives. So, it is easy to control the tilt of a surface to adjust interference fringe.

» Long Measuring Range

270um Long PZT scanning range can cover most of the measuring needs up to 10mm. (option)

» Selectable F.O.V & Objective lens

You can select a variety of F.O.V lens 0.55x, 0.75x, 1.0x, 2.0x and interferometric objectives 2.5x, 5x, 10x, 20x, 50x. Super long working distance objectives are also available.

» Large Travel XY Stage

Motorized 100x100mm travel XY stage help you to measure large size workpieces. For large area(Stitching function is available) & Back-light illumination are available. (Option)

» Powerful Software

Cutting edge real time 3D imaging of surface topography. Automate analysis and publish results easily. The latest ISO25178 standards and national standard.

Advanced Operating and Analysis Software

» NanoView : Operating Program

NanoView 🕫

The Operating Program based on a user-friendly GUI configuration is easy and simple to use. And because of its excellent reproducibility, everyone can get the same measurement value.



With GFM function, it is possible to measure 2D size easily by tracing the required areas on screen(Diameter, Width, Pitch, Distance, etc). This is convenient when the sample to be observed has an irregular shape.



Circle Shape







NanoMap intuitively displays the measurement results and can obtain the desired level of fine step, roughness, and 3D analysis data through 2D analysis, Multi analysis, 3D analysis.



» Stitching Function

Stitching is a process organizing a map by stitching several unit measurement results. It allows analyzing all the patterns in large area, while surveying or measuring the detailed pattern using necessary magnification.

By using the Stitching function, it is possible to measure large areas beyond the existing lens magnification.





By using Stitching function, it is possible to measure up to several tens of mm.



PCB Warpage

» Multi Analysis

Multi analysis function allows user to compare profiles, roughness information and step information at a glance.











NanoMap Alpha: **Advanced Analysis Program**



» Acquire ISO9001:2000 (Certification Number : K-QA-Q041816)

Compliance with the ISO and national standards : Analysis of surface texture, roughness, waviness, flatness, grains etc. NanoSystem has surface analysis and filtering technologies and it's NanoMap Alpha. NanoMap Alpha® integrates parameters defined by the latest ISO standards, ASME B46.1 (USA) standards and many other international standards .

» Various types of surface information can be analyzed.



Profile analysis : profiles, series of profiles, contour etc.



Surface analysis : surface topography, series of topographies etc.



Multi-physics : topography + color + intensity etc.



Image analysis : binary image, grayscale image, color image, series of images.



> Hyper-spectral analysis : spectrum, series of spectra, hyperspectral cube etc.







ISO 25178 Height Parameters			ISO 4287 Amplitude parameters - Roughness profile				
Ssk	-0.181		Skewness	Rv	0.532	μm	Maximum valley depth of the roughness profile.
Sku	2.87		Kurtosis	Rz	1.07	μm	Maximum Height of roughness profile.
Sp	1.60	μm	Maximumpeakheight	Rc	0.683	μm	Mean height of the roughness profile elements.
Sv	1.97	μm	Maximum pitheight	Rt	1.65	μm	Total height of roughness profile.
Sz	3.57	μm	Maximum height	Ra	0.212	μm	Arithmetic mean deviation of the roughness profile.
Sa	0.340	μm	Arithmetic meanheight	Rq	0.262	μm	Root-mean-square (RMS) deviation of the roughness profile.
Hybrid Parameters		Rsk	0.00967		Skewness of the roughness profile.		
Sdr	65.0	%	Developed interfacial area ratio	Rku	2.61		Kurtosis of the roughness profile.





Save as Minidoc





Specifications

Model	NV-1800	NV-2400	NV-2700	NV-3200			
Production / Measurement Method	White Light Scanning Interferometry / Phase Shift Interferometry						
F.O.V Lens	1.0x (D)efault)	4 Position Motorized Turret Addition F.O.V Available (Option)				
Interferometric Objectives	Single Lens Available	5Lens Available (Manual Turret)	5Lens Available (Motorized Turret)				
Illumination	White Light LED Illumination						
Scanning Range	≤ 270um (PZT Scanning)						
Scanning Velocity	7. 2um/sec (1x~3x user selectable)	12um/sec (1x~5x user selectable)					
Tip / Tilt	±3° (Stage Tip/Tilt)	Probe Tip/Tilt ±6° (Manual)	Tip/Tilt torized)				
Vertical Resolution	WSI : 0.5nm / PSI : 0.1nm						
Lateral Resolution	0.2 ~ 4um (Objectives / FOV Lens Dependent)						
Step Height Repeatability	0.2% @1o	0.1% @1σ(Standard 8um Step sample)					
X, Y Stroke	70x50mm (Manual)	100x100mm	300x300mm (Motorized)				
Z Stroke	30mm (Manual)	100mm (Manual) 100mi		Notorized)			
Stage Size	90x90mm	230x2	445x445mm				
	Option						
F.O.V Lens	0.5x, 0.75x, 1x, 1.5x, 2x (Selectable)						
Interferometric Objectives	2.5x, 5x, 10x, 20x, 50x, 100x (Selectable)						
Vacuum Stage	Option						
Scanning Range	Max 10mm available (Motor Scanning Option)						

\gg Product Dimension (NV-2700 Model)





Advanced Measuring Technology



- Premium Model
- Motorized Turret
- Motorized Stage(XY): 300 X 300mm
- Auto focus
- F.O.V lens selectable
- Stitching function



- Economic Model
- 5 objective lens Select able (Manual)
- Motorized Stage(XY): 100 x 100mm
- Stitching function





- Advanced Model
- Motorized Turret
- Motorized Stage(XY) : 100 X 100mm
- Auto Focus

- F.O.V lens selectable
- Stitching function



- Compact model
- Single lens type
- Manual Stage(XY) : 70 x 50mm
- Excellent measuring accuracy











6 Resistance (objective lens 5x / optical zoom 1x / scanning area 13mm x 13mm) 6 Wafer on laser marking (objective lens 50x / optical zoom 1x / scanning area 250μm x 150μm)

ManoSystem







» Characteristics

- Easy Manipulation S/W for Measuring
- Reliability and Prompt Support
- 2/3D Multi-functional Performance

» 3D Metrology Pad / Land Algorithm

» 3D Metrology Trace Line / Space Width Algorithm

NVM Series : Non-contact 3D Surface Measuring Automation System

Automated Non-contact Optical Measurement Machine Surface Profiler has Nano Resolution using Optical Interference High Resolution CNC Programmable Automatic Optical Coordinate Measurement

NVM - Series is an automatic 3D inspection system for High-end PCB Process Monitoring

- Recipe Function (2/3D all in one function)
- Automatic Measuring Function (2/3D Auto Module Change)
- Auto Focus Function
- Data Feedback Function (Same output)

• Texture analysis Roughness parameter • Wear analysis compliant with DIN EN SIO

» Non-destructive measurement of cylinder bore surfaces

The CylinderScan combines exceptional non-destructive profiling performance, operator convenience.

Tribology, bearing surfaces, functional volume

» Volume parameters Compliance with ISO 25178

» Sk parameters Compliance with ISO 13565-2

- 3D roughness parameters
- Defect detection
- The topography of the cylinder surface is one of the most important factors to control oil consumption, fuel consumption, longevity and wear of engines. In order to enhance surfaces, CylinderScan is a reliable method to characterize them.

• Volume parameters

- Besides evaluating ISO roughness values, employing white light interferometry, this compact system can measure 3D
- surface topography from nanometer-scale roughness with sub-nanometer resolution and production-level throughput.
- It allows to measure cylinder bores from 70 to 160mm diameter. It is fully automated with handful recipe function(radial, axial).

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